



MicroNanoFabrication Annual Review Meeting

Date : mardi 18 mai 2004
Heures : 09h00 – 17h00
Lieu : Salle Polyvalente, Centre Est, CE 1 515

Programme :

- 09h00-09h40** Cafés et Croissants, Distribution des Badges et des Proceedings
- 09h40-09h45 **Prof. S. Catsicas** (EPFL), Message du Vice-Président de l'EPFL
- 09h45-10h00 **Prof. Ph. Renaud** (CMI) & **Ph. Flückiger** (CMI), Introduction
- 10h00-10h30 **F. Sermet** (Managing Director, Development Economic Western Switzerland), Attractivité de la Suisse
- 10h30-11h00 **S. Neylon** (CEO Colibrys SA), Challenges in Converting Horizontal Technology Capabilities into Valued Market-Driven Products
- 11h00-11h30 **W. Noell** (IMT), MEMS for Watches
- 11h30-12h00 **Prof. A. Ionescu** (EPFL), Emerging Nanoelectronics
- 12H00-12H10 **Prof. Ph. Renaud** (CMI), Nano2Life Network of Excellence
- 12h10-13h20** **Buffet, Session Posters**
- 13h20-13h40 **Prof. H. Brune** (EPFL), Fabrication of an Addressable Hot Electron Emitter Based on the Tunnel Effect
- 13h40-14h00 **R. Stanley** (CSEM), Novel Approaches to Manipulating Fibers on Silicon
- 14h00-14h20 **O. Guenat** (IMT), Development of a Multifunctional Platform for Cell Cultures
- 14h20-14h40 **Prof. H. Girault** (EPFL), Micro Systèmes d'Analyse. Prototypage par Photo-Ablation Laser, Production par Usinage Plasma
- 14h40-15h15** **Pause, Session Posters, Rafrâichissements** **POSTERS COMLAB !**
- 15h15-15h30 **C. Hibert** (CMI & NMRC), State-of-the-art DRIE Processing
- 15h30-15h45 **G.-A. Racine** (CMI), Photolithography Developments at CMI
- 15h45-16h05 **M. Pavius** (CMI), Focused Ion Beam Facility at CMI
M. Cantoni (CIME), TEM Lamella Preparation and Analysis
- 16h05-17h00** **Apéritif, Session Posters** **POSTERS CMI !**